

(113)B GaAs ウエハ接合で作製した GaAs/AlGaAs 多層膜結合共振器への 電流注入によるレーザ発振

Current-injection lasing from a GaAs/AlGaAs coupled multilayer cavity

fabricated by (113)B GaAs wafer bonding

徳島大院¹, 産総研², 千葉大院³ ◯盧翔孟¹, 小楠洸太郎¹, 高橋美沙¹, 合田剛史¹,

熊谷直人², 森田健³, 南康夫¹, 北田貴弘¹

Tokushima Univ.¹, AIST², Chiba Univ.³ ◯Xiangmeng Lu¹, Kotaro Ogusu¹, Misa Takahashi¹,
Tsuyoshi Goda¹, Naoto Kumagai², Ken Morita³, Yasuo Minami¹, Takahiro Kitada¹

E-mail: xm-lu@tokushima-u.ac.jp

We have proposed a novel terahertz (THz) emission device based on difference-frequency generation (DFG) in a GaAs/AlGaAs coupled multilayer cavity structure.^[1] To obtain a larger THz DFG signal, it is necessary to control the nonlinear polarization via the face-to-face bonding of two epitaxial wafers.^[2] We have demonstrated a current-injection two-color lasing in the coupled multilayer cavity, which was fabricated by bonding of (001) and (113) epitaxial wafers.^[3,4] Since the effective second-order nonlinear coefficient is zero on a (001) GaAs, stronger polarization and DFG are enabled if two (113)B epitaxial wafers were bonded.

In this study, a coupled cavity structure was fabricated by the face-to-face bonding of two (113)B epitaxial wafers. The schematic of the current-injection device based on the coupled cavity structure was shown in Fig. 1. InGaAs multilayer quantum well were embedded in the upper cavity as gain materials. Optical emission properties of the devices were studied using a pulsed-current source with a repetition rate of 1 kHz and a pulse duration of 0.5 μs. Figure 2 shows the spectra measure at room temperature. Two emission peaks due to the cavity modes were observed at a current of 25 mA. Oscillation of long-wavelength mode was observed at a current of 60 mA. Long-wavelength mode shows a threshold at approximately 40 mA.

[1] T. Kitada *et al.*, APL. **95**, 111106 (2009). [2] T. Kitada *et al.*, APL.**102**, 251118 (2013). [3] Y. Minami *et al.*, JJAP. **56**, 04CH01 (2017). [4] T. Kitada *et al.*, JJAP. **57**, 04FH03 (2018).

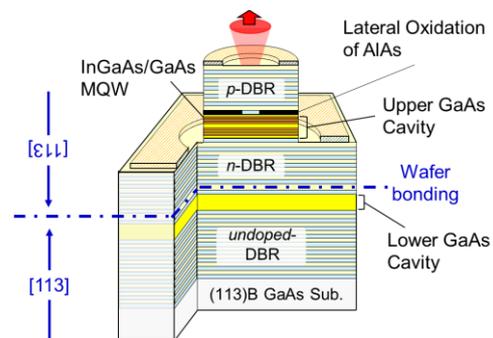


Fig. 1. Schematic of device

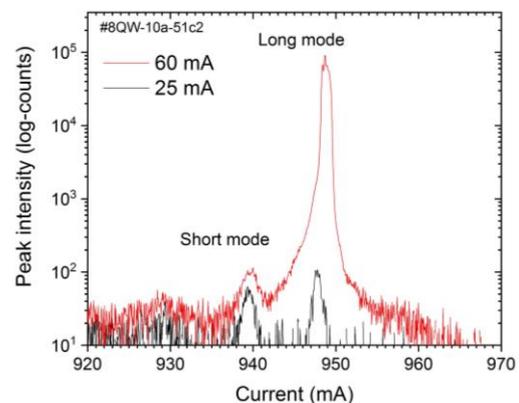


Fig. 2 Emission spectra of device